



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

U.S. Serial No. 10/750,251) I hereby certify that this paper (and/or fee)
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Applicants: Young Hun Seo) Postal Service as first class mail in an
) envelope addressed to:
Title: Method For Fabricating)
Silicon on Insulator Substrates) Mail Stop Amendment
For Use In Semiconductor) Commissioner for Patents
Devices) P.O. Box 1450
) Alexandria, VA 22313-1450
Filed: December 31, 2003) on this date:
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TC/AU: 2826) Dated: August 12, 2005
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Examiner: Pert	$\frac{1}{2}$
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Docket No.: 20059/PIA31199	Mark C. Zimmerman
) Registration No. 44,006
	,

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

RESPONSE TO THE OFFICE ACTION DATED MAY 12, 2005

Dear Sir:

Please enter the following amendments and consider the following remarks.

Changes to the Specification begin on page 2 of this paper.

The Status of the Claims is reflected in the listing of claims that begins on page 3 of this paper.

Remarks begin on page 4 of this paper.